## **AMENDMENTS TO THE CLAIMS**

Please amend claims 1-16 and 19-24, cancel claims 17, 18, 25 and 26, and add new claims 27 and 28 as follows:

- 1. (currently amended) A semiconductor optical waveguide device, comprising a semiconductor layer having an upper surface, and a lower surface which is defined by a lower confinement layer, the semiconductor layer having formed therein:
  - (a) a waveguide;
  - (b) at least one recess adjacent to the waveguide and extending from the upper surface of the semiconductor layer;
  - (c) at least one doped region, at least part of which is situated between a said the recess and the lower confinement layer; and
  - (d) at least one trench adjacent to a said the doped region and the recess and situated on an opposite side thereof to the waveguide, wherein the (or each) trench extends from the upper surface of the semiconductor layer.
- 2. (currently amended) A device according to Claim 1, wherein the (or each) trench is deeper than its the adjacent recess.
- 3. (currently amended) A device according to Claim 1-or Claim 2, in which wherein the (or each)-recess is spaced apart from its-the adjacent trench.
- 4. (currently amended) A device according to Claim 1-or-Claim 2, in which wherein the (or each)-recess is not spaced apart from its-the adjacent trench, so that the recess and the trench comprise a single larger feature.
- (currently amended) A device according to any preceding claim 1, in which
   wherein the (or each) doped region extends substantially to the lower confinement layer.

6. (currently amended) A semiconductor optical waveguide device, comprising a semiconductor layer having an upper surface, and a lower surface which is defined by a lower confinement layer, the semiconductor layer having formed therein:

- (a) a waveguide;
- (b) at least one doped region extending substantially to the lower confinement layer; and
- (c) at least one trench adjacent to, and spaced apart from, a said the doped region and situated on an opposite side thereof to the waveguide, wherein the (or each) trench extends from the upper surface of the semiconductor layer.
- 7. (currently amended) A device according to <u>Claim 6, any preceding claim, in which</u>

  wherein the (or each) trench extends substantially to the lower confinement layer.
- 8. (currently amended) A device according to <u>Claim 6, any preceding claim, in which</u>

  wherein the waveguide is a rib waveguide, <u>comprising having</u> a rib portion.
- (currently amended) A device according to <u>Claim 6, any-preceding claim, in which</u>
   <u>wherein the semiconductor layer comprises silicon.</u>
- (currently amended) A device according to <u>Claim 6, any preceding claim, in which</u>
   <u>wherein the lower confinement layer is a confinement layer for electrical charge carriers.</u>
- 11. (currently amended) A device according to <u>Claim 6, any preceding claim, in which</u>

  <u>wherein</u> the lower confinement layer is a confinement layer for an optical mode

  propagated by the waveguide.

12. (currently amended) A device according to <u>Claim 6, any preceding claim, in which</u>
wherein the lower confinement layer is an electrically insulating layer.

- 13. (currently amended) A device according <u>Claim 6</u>, to any preceding claim, in which wherein the lower confinement layer comprises silica.
- 14. (currently amended) A device according to <u>Claim 6, any preceding claim, in which there</u>
  is <u>further comprising</u> a substrate layer below the lower confinement layer.
- 15. (currently amended) A device according to Claim 14, in which wherein the substrate layer comprises silicon.
- 16. (currently amended) A device according to <u>Claim 6</u>, any preceding claim, in which there are <u>further comprising</u> two <u>of</u> said doped regions, the doped regions being situated on opposite sides of the waveguide.
- 17. (cancelled)
- 18. (cancelled)
- 19. (currently amended) A device according to Claim 8, 18 when dependent upon Claim 8, in which the further comprising an additional doped region is situated in the rib portion of the rib waveguide.

20. (currently amended) A device according to <u>Claim 6</u>, any preceding claim, in which there are <u>further comprising</u> two <u>of said trenches</u>, the trenches being situated on opposite sides of the waveguide.

- 21. (currently amended) A device according to Claim 16, or any claim dependent thereon, in which wherein the doped regions comprise n-doped and p-doped regions.
- 22. (currently amended) A device according to <u>Claim 6, any preceding claim, which comprises further comprising</u> a p-i-n diode.
- 23. (currently amended) A device according to Claim 22, which comprises wherein the p-i-n diode comprises a lateral p-i-n diode.
- 24. (currently amended) A device according to <u>Claim 6</u>, any preceding claim, which emprises <u>further comprising</u> an optical modulator.
- 25. (cancelled)
- 26. (cancelled)
- 27. (new) A device according to Claim 2, further comprising two of said recesses, the recesses being situated on opposite sides of the waveguide.
  - 28. (new) A device according to Claim 1, further comprising an additional doped region.